

# AST-200H

Advanced Detection and Metrology  
System with Wafer Handling

- Defect Detection & Classification
- Infrared and Visible Spectrums
- Precision Dimensional Metrology
- Automatic and Manual Operation
- Up to 300mm Wafer/Part Capacity

This top performance system is designed for applications where high-speed defect detection and precision measurements on wafers and other parts are required. It is well suited for use as a dedicated production tool or as a versatile process development system. It features a powerful set of automated as well as semi-automatic optical/video tools optimized for high accuracy, production throughput, and ease of use.

This automated and versatile platform can be configured with specialized optical paths across the spectrum utilizing precise part staging. The system offers significant and unique advantages for dual production/engineering use, and provides the perfect solution when both defect detection and dimensional metrology are required.

The system can be configured or customized to meet your exact requirements with a variety of optical and illumination accessories, custom wafer/part fixtures, as well as custom operator interface, data formats and reports.



## APPLICATIONS

---

- Wafer level defect detection & measurement
- Infrared and Visible Spectrums
- Precision MEMS and HD component inspection
- Advanced microelectronics package inspection

## POWERFUL

---

- Designed for automatic/semi-automatic operation
- Extensive defect detection features & capability
- Integrated dimensional metrology features

## PRECISE

---

- Sub-micron precision optical measurements
- High accuracy staging with 0.02  $\mu\text{m}$  linear encoder resolution

## FAST

---

- Up to 10 field of views per second - application dependent.
- 200mm/second part staging speed

## USER FRIENDLY

---

- Very easy to use, program and set up
- Highly visual data with rich color graphics & video

## FLEXIBLE

---

- Specialized optics and other advanced options
- Optional wafer and other part types handling
- Customizable for application specific solutions

# AST-200H

Advanced Detection and Metrology System with Wafer Handling

## SPECIFICATIONS

### PLATFORM:

- 200mm (optional 300mm) wafer/part size capacity
- Maximum stage Load capacity: 50 lb
- 250mm/second maximum staging speed
- Granite base and Z-column, stainless steel finish
- Class 100 (10 optional) clean room compatible
- Closed loop linear stages, with position feedback from 0.02  $\mu\text{m}$  resolution linear glass encoders
- Non-linear 2D accuracy error correction

### ACCURACY (XY):

- 1.5+0.6L100  $\mu\text{m}$ , U1 (z): 1.5+3L/100  $\mu\text{m}$ . Where L is length in mm

### COMPUTER:

- Windows 7 Pro

### OPTICAL SYSTEM:

- Flat Field objectives, with motorized 5 position turret

### CAMERA:

- High resolution CCD array 60+db S/N ratio
- Image Processing 256 grayscale with 1:5-1:50 sub-pixel ratio
- Video and optional Laser Auto focus

### ILLUMINATION:

- Software controlled Coaxial & backlight

### OTHER:

- Environmental: 17-23 deg C, 20-80% Humidity
- Electrical: 120/240 VAC, 15A single phase
- Footprint: WxD: 32x36 inches, Height: 67 inches
- Weight: 2100 lbs. crated

### SOFTWARE FEATURES:

- Automatic defect detection and classification
- Graphical Defects maps, Image Archival, offline review of defects, and reprocessing of archived images
- Flexible part scanning for operator convenience and throughput optimization
- High Precision vision based part alignment

### DIMENSIONAL METROLOGY TOOLS:

- **Video Tools:** Point, Line, Circle, Arc edge detectors with built in best fit and defect removal
- **Constructions:** Extensive geometric constructions, with distance and angle measurements (e.g. line to line, etc.)
- **Origin & Skew:** Unlimited reference frames
- **Tolerancing:** Dimensional, Angular, Geometric True Position (MMC, LMC, RFS)
- **Units:** Metric & inches
- **Coordinates:** Cartesian & Polar
- **Step & Repeat:** Repeat Loops for repeating features and multiple parts
- **Reports:** Data on screen, text file, or exports to Excel
- **SPC:** Average, SD, Range, Min, Max, Cp, Cpk
- **Graphics & CAD:** Drawing import/Export
- **Other:** Auto Focus, Auto Lighting & Outlier Removal

***AST carries a complete line of precision devices to accommodate your inspection, metrology, and infrared imaging requirements. We also specialize in assembling customized systems, built to your specific need. Call us today for a consultation.***